

RECEIVED
CENTRAL FAX CENTER

:5167424366

6/ 25

MAY 0 4 2004

OFFICIAL

RESPONSE UNDER 37 CFR § 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2813IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Jack O. Chu, et al.

Examiner: E.J. Kielin

Serial No.: 09/692,606

Art Unit: 2813

Filed: October 19, 2000

Docket: YOR920000344US1 (17178)

For: LAYER TRANSFER OF LOW DEFECT
SiGe USING AN ETCH-BACK PROCESS

Dated: May 4, 2004

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450RESPONSE UNDER 37 C.F.R. § 1.116

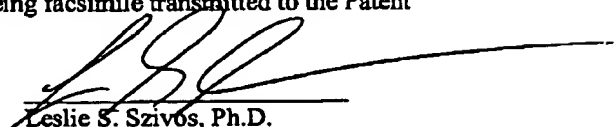
Sir:

In response to the Office Action dated March 4, 2004, applicants submit the following amendments and remarks for entry of record in the above-identified patent application.

CERTIFICATION OF FACSIMILE TRANSMISSION

I hereby certify that this paper is being facsimile transmitted to the Patent and Trademark Office on the date shown below.

Dated: May 4, 2004


Leslie S. Szivos, Ph.D.DO NOT ENTER
CR 5/10/2004